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(54) **Title**: INTEGRATED MICROMINIATURE RELAY

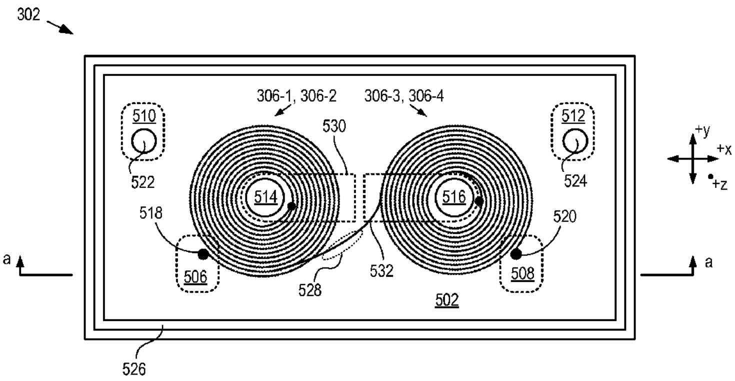

FIG. 5A

(57) **Abstract**: A micro-relay that overcomes some of the limitations and drawbacks of the prior art is disclosed. The micro-relay comprising : (1) a first substrate comprising one or more monolithically integrated planar coils for generating a magnetic field; and (2) a second substrate comprising a magnetically actuated switch having a moving contact that selectively moves in a plane parallel to its substrate. The first and second substrate are aligned and bonded to collectively provide a closed magnetic circuit that efficiently channels the generated magnetic field through the switch.

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Integrated Microminiature Relay

Cross Reference to Related Applications

[0001] The underlying concepts, but not necessarily the language, of the following cases are incorporated by reference:

(1) U.S. Patent Application Publication 20090237188 A1, published September 24, 2009; and
(2) U.S. Patent 6,094,116, issued July 25, 2000; and
(3) U.S. Patent 6,366,186, issued April 2, 2002.

If there are any contradictions or inconsistencies in language between this application and one or more of the cases that have been incorporated by reference that might affect the interpretation of the claims in this case, the claims in this case should be interpreted to be consistent with the language in this case.

Field of the Invention

[0002] The present invention relates to magnetically actuated actuators in general, and, more particularly, to magnetically actuated micro-relays.

Background of the Invention

[0003] Relays are electrical switching devices that use the flow of a first current to control the flow of a second current. A relay normally comprises two primary components: (1) an electromagnetic coil for generating a magnetic field based on the flow of the first current; and (2) a magnetically actuated electrical switch for controlling the second current, wherein the switch is actuated by the generated magnetic field.

[0004] Electromagnetic relays with electrical contacts are commonly comprised of a working gap that connects and disconnects the contacts, and an electromagnetic coil which produces a magnetic field that couples to the working gap via a magnetic path. To provide efficient coupling between coil and the working gap a readily magnetized or “soft” ferromagnetic material may be employed in the magnetic path. Further improvement in coupling is obtained when the soft ferromagnetic path is compact and consequently short with large cross sectional area. The force exerted on the relay contacts due to the magnetic field produced by the electromagnetic coil is a function of the material used in the device, the geometry of the coil, the number of turns in the coil itself, and the magnitude of the first current. Typically, the coil includes a large number of turns to keep the magnitude of the first current small.

[0005] In recent years, new microfabrication technologies, such as Micro-Electro Mechanical Systems (MEMS) technology, have been applied to the fabrication of relays. MEMS technology is based on planar processing operations that were first developed for use in the integrated circuit industry; however, MEMS technology affords the ability to form structures that are movable relative to their substrate. MEMS technology enables the fabrication of micro-relays that have several advantages over their macro counterparts, such as smaller size, lower cost due to the use of low-cost batch manufacturing, and new device functionality and applications that are enabled by their small size.

[0006] Prior-art micro-relays employ switches based on mechanically active switching elements such cantilever beams, doubly supported beams (*i.e.*, bridges), plates, and membranes. These moving structures typically comprise a movable magnetic element comprising a first electrical contact. A magnetic field is applied to the magnetic element, which moves the first electrical contact into, or out of, contact with a second electrical contact (or pair of contacts) to enable or disable the flow of the second current.

[0007] Vertically actuated micro-relays comprise magnetic elements whose motion is enabled in a direction that is perpendicular to its underlying substrate. The creation of the movable structure in such a configuration is relatively straight-forward using conventional MEMS-based planar processing techniques. Using planar processing to add an efficient magnetic circuit having a compact magnetic path and large cross section area to such a structure is a challenge, however. In addition, the operating characteristics of such relays are primarily determined by the thin-film properties of the layers from which the movable magnetic elements are formed. The mechanical properties of thin-film layers can vary significantly depending on deposition conditions, however. Such variation can result in inconsistent operating characteristics even among micro-relays of the same design.

[0008] Laterally actuated micro-relays comprise magnetic elements whose motion is enabled along a plane that is substantially parallel to its underlying substrate. The magnetic element is typically supported above the substrate by tethers designed to be resilient for in-plane (*i.e.*, lateral) motion but stiff for out-of-plane (*i.e.*, vertical) motion. The tethers and magnetic elements are defined by photolithography and etching to “sculpt” them into their desired shape. Such micro-relays avoid some of the problems associated with vertically actuated micro-relays. In particular, the operating characteristics (*e.g.*, resiliency, actuation force, operating speed, *etc.*) of a laterally actuated micro-relay depend more upon the defined structure of its tethers than upon the thin-film properties of the layers from which they are formed. As a result, the operating characteristics are substantially decoupled from deleterious effects due to film stress, thickness variations, and the like.

[0009] Typically, it is most desirable to use an electromagnetic coil to control the magnetic field that actuates a micro-relay, whether the magnetic field is generated by a permanent magnet or by the electromagnetic coil itself. Implementing an electromagnetic coil within a batch wafer-level process can be quite challenging, however, due to the three-dimensional character of such a coil and the need to efficiently magnetically couple it to the movable magnetic element. Thus, unfortunately, it is difficult at best to produce a practical integrated coil that can reliably actuate these switching elements.

[0010] As a result, micro-relays in the prior art have typically relied upon poorly coupled coils or external, non-integrated coils to provide the magnetic field for actuation. With a poorly coupled coil, however, the consequent large electrical power required to energize the relay is a significant drawback. The use of an externally configured coil not only adds significant packaging cost and size, but typically poor assembly tolerances can lead to significant variation in the operating characteristics of micro-relays of the same design.

Summary of the Invention

[0011] The present invention provides a microfabricated micro-relay that overcomes some of the limitations and drawbacks of the prior art. Embodiments of the present invention comprise: (1) a magnetically actuated electrical switch having a moving contact that selectively moves in a plane parallel to its substrate; (2) one or more integrated planar coils for generating a magnetic field that actuates the electrical switch; and (3) a closed magnetic circuit for efficiently channeling the magnetic field through the electrical switch.

[0012] The planar coil is monolithically integrated on a first substrate that comprises a first portion of the magnetic circuit. The electrical switch is monolithically integrated on a second substrate that comprises a second portion of the magnetic circuit. The first and second substrates are aligned and bonded to complete the closed magnetic circuit and integrate the coil and switch in the micro-relay. The completed magnetic circuit efficiently channels the generated magnetic field through the switch, which reduces the magnitude of the magnetic field that must be generated by the planar coil.

[0013] In some embodiments, the closed magnetic circuit comprises two magnetic cores. Each magnetic core comprises ferromagnetic elements formed in each of first and second substrates. In addition, portions of each magnetic core collectively define the electrical switch.

[0014] An embodiment of the present invention comprises a plurality of coils that are arranged such that the magnetic field generated by one coil is augmented by the remaining coils. As a result, the plurality of coils collectively generates a magnetic field having high field strength.

[0015] In some embodiments, multiple electromagnetic modules, each comprising at least one planar coil, are arranged such that the coils collectively generate a magnetic field. Each electromagnetic module further comprises magnetic vias and electrical vias for magnetically and electrically coupling the substrates.

[0016] An embodiment of the present invention comprises: a first substrate comprising a first coil for generating a magnetic field, wherein the coil is substantially planar and lies in a first plane, and wherein the first coil and the first substrate are monolithically integrated; and a second substrate comprising an electrical switch that comprises a first electrical contact and a second electrical contact, wherein the first electrical contact is moved by the magnetic field, and wherein the electrical switch and the second substrate are monolithically integrated, and further wherein the first electrical contact moves selectively in a second plane that is substantially parallel to the first plane.

Brief Description of the Drawings

[0017] FIG. 1 depicts a schematic drawing of a first micro-relay in accordance with the prior art.

[0018] FIG. 2 depicts a schematic drawing of a second micro-relay in accordance with the prior art.

[0019] FIG. 3 depicts a simplified cross-sectional schematic drawing of a micro-relay in accordance with an illustrative embodiment of the present invention.

[0020] FIG. 4 depicts operations of a method for forming a micro-relay in accordance with the illustrative embodiment of the present invention.

[0021] FIGS. 5A and 5B depict schematic drawings of a top view and cross-sectional view through line a-a, respectively, of electromagnetic module **302**.

[0022] FIG. 6 depicts sub-operations suitable for use in operation **401**, wherein electromagnetic module **302** is formed in accordance with the illustrative embodiment of the present invention.

[0023] FIGS. 7A and 7B depict schematic drawings of a top view and cross-sectional view through line b-b, respectively, of actuator module **304**.

[0024] FIG. 8 depicts sub-operations suitable for use in operation **402**, wherein actuator module **304** is formed in accordance with the illustrative embodiment of the present invention.

[0025] FIG. 9 depicts a cross-sectional view of fully assembled relay **300** in accordance with the illustrative embodiment of the present invention.

[0026] FIG. 10 depicts a magnetic circuit in accordance with the illustrative embodiment of the present invention.

[0027] FIG. 11 depicts a schematic diagram of a simplified cross-sectional view of a micro-relay in accordance with a first alternative embodiment of the present invention.

Detailed Description

[0028] The following terms are defined for use in this Specification, including the appended claims:

- **Electrically connected** is defined as a state in which two or more points are connected such that they are at substantially the same voltage level at any current level. This can be via direct physical contact (*e.g.*, a contact pad physically coupled with an electrical via, *etc.*) or through an electrically conductive intermediate (*e.g.*, nodes of a circuit interconnected by a conductive wire or trace, *etc.*).
- **Electrically coupled** is defined as a state in which two points are in electrical communication. This can be via direct physical contact (*e.g.*, a plug in an electrical outlet, *etc.*), via an electrically conductive intermediate (*e.g.*, electrical devices connected by a conductive wire or trace, *etc.*), or via intermediate devices, *etc.* (*e.g.*, electrical devices connected through a resistor, inductor, *etc.*).

[0029] FIG. 1 depicts a schematic drawing of a first micro-relay in accordance with the prior art. Relay **100** comprises magnetic elements **102** and **104**, coil **108**, cantilever beam **110**, electrical contacts **116** and **118**, and substrate **120**. Examples of relays such as relay **100** are disclosed by Tai, *et al*. in U.S Patent 6,094,116, issued July 25, 2000, which is incorporated herein by reference.

[0030] Magnetic element **102** is a layer of ferromagnetic material that is formed on the surface of substrate **120**. Ferromagnetic material is material that has moderate or high magnetic permeability and is capable of channeling a magnetic field. Examples of ferromagnetic materials include permanent magnet material, nickel, nickel-iron alloy, iron, permalloy, supermalloy, Sendust™, and the like.

[0031] Magnetic element **104** is also a layer of ferromagnetic material that is formed on substrate **120** such that magnetic elements **104** overlaps magnetic element **102** in region **106**. Magnetic element **104** is fabricated using conventional planar processing operations such as those included in a MEMS fabrication process. Magnetic element **104** is formed having cantilever beam **110** whose free end **112** is suspended over magnetic element **102** at region **114** to form an air gap. Free end **112** is also suspended over electrical contacts **116** and **118**.

[0032] Coil **108** is a planar coil of electrically conductive material, which is electrically connected to magnetic element **102**. When a first current flows through coil **108**, it generates a magnetic field. Coil **108** is wrapped around region **106** such that the magnetic couples into magnetic elements **102** and **104**. Further, magnetic elements **102** and **104** and coil **108** collectively define a magnetic circuit that channels the magnetic field through the air gap located at region **114**.

[0033] In response to the magnetic field, a magnetic force is developed on cantilever beam **110** that pulls free end **112** vertically downward (*i.e.*, in a direction that is orthogonal with the plane of coil **108** and substrate **120**) and toward magnetic element **102**. As a result, free end **112** makes contact with substrate **120** and electrically shorts electrical contacts **116** and **118** thereby enabling the flow of current **120**.

[0034] Relay **100** suffers from several disadvantages. First, it relies upon the fact that the planar coil and switching element are arranged in close proximity and that the switching element moves in a direction perpendicular to the plane of the coil. As disclosed by Tai: "the two layers of magnetic material 1, 4 overlap each other at one point 5 about which the coil 3 is wrapped. This creates a planar solenoid that is very efficient at generating magnetic force." See *e.g.*, Col. 5, lines 26-29 and FIG. 1. In addition, due to the small thickness of the magnetic circuit elements **102** and **104**, the magnetic reluctance of the return magnetic circuit is high. As a result, the efficiency of the coupling between the magnetic field produced by coil **108** and the magnetic flux induced in the air gap **114** is low. A greater magneto-motive force from the coil is required, therefore, to produce a magnetic flux density in the air gap near the saturation flux density of the return magnetic circuit material. This magneto-motive force can be increased by either increasing the electric current through coil **108** or by increasing the number of turns included in coil **108**. When higher current is used, the relay consumes much more power. When more coil turns are used, the planar layout of the magnetic circuit requires that the magnetic return path becomes substantially greater. This further increases magnetic reluctance and, therefore, further reduces coupling efficiency.

[0035] Since cantilever **112** moves in a direction perpendicular to the planes of coil **108** and substrate **120**, the thickness and material properties of the layer from which the cantilever is formed primarily determine the mechanical behavior of the cantilever. For example, the required driving force, restoring force, resonant frequency, *etc.* are based on the thickness, density, residual stress, and residual stress gradient through the thickness of cantilever **112**. Variations in these material properties from deposition to deposition are typical. As a result, the fact that cantilever **112** moves in a direction perpendicular to substrate **120** leads to:

i. variations in the operating characteristics of relay **100**; or
ii. inconsistent operating characteristics between different relays of the same design; or
iii. repeatability and reliability issues; or
iv. variation in the contact resistance between free end **112** and each of electrical contacts **116** and **118** from relay to relay; or
v. any combination of i, ii, iii, and iv.

[0036] Furthermore, the thickness of cantilever **112** is often limited to a maximum deposition thickness inherent to the deposition process used to form the cantilever layer. The design space for relays such as relay **100** is, therefore, limited.

[0037] FIG. 2 depicts a schematic drawing of a second micro-relay in accordance with the prior art. Relay **200** comprises magnetic elements **202**, **204**, and **206**, springs **208** and **220**, anchors **210** and **222**, electrical contact **212**, tether **214**, electrical lines **216** and **218**, and substrate **224**. Examples of relays such as relay **200** are disclosed by Hill, *et al.* in U.S Patent 6,366,186, issued April 2, 2002, which is incorporated herein by reference.

[0038] Magnetic elements **202** and **204** are layers of ferromagnetic material formed on the surface of substrate **224**. Magnetic elements **202** and **204** collectively define a "magnetic flux path" for channeling an externally applied magnetic field.

[0039] Magnetic element **206** is an element comprising ferromagnetic material. Magnetic element **206** is suspended above substrate **224** by means of spring **208**.

[0040] Spring **208** is a loop of structural material, such as silicon, polysilicon, *etc.* Spring **208** is formed into an oval shape using a conventional MEMS fabrication technique, such as deep reactive-ion etching (DRIE). Spring **208** is supported by anchor **210** above substrate **224**. Spring **208** is substantially planar and lies in a first plane that is above and substantially parallel to a second plane that is defined by substrate **224**.

[0041] By virtue of its shape, spring **208** is resilient in the first plane, but resistant to bending out of the first plane. Magnetic element **206** is attached to spring **208** such that it is also suspended above substrate **224**. As a result, motion of magnetic element **206** in the first plane is enabled but motion of magnetic element **206** out of the first plane is inhibited.

[0042] Magnetic elements **202** and **204** are arranged to channel a magnetic field through magnetic element **206** and the gaps that separate the three magnetic elements. In operation, the magnetic field is externally applied by moving a magnetic element into proximity with relay **200**.

[0043] Spring **220** is a curved structural element that is suspended above substrate **224** by anchors **222** and lies in the first plane. Similar to spring **208**, spring **220** is resilient in the first plane but resists bending out of the first plane.

[0044] Electrical contact **212** is an electrically conductive element that is attached to spring **220** such that electrical contact **212** is suspended above substrate **224**. As a result, motion of electrical contact **212** in the first plane is enabled but motion of electrical contact **212** out of the first plane is inhibited.

[0045] Tether **214** rigidly couples magnetic element **206** and electrical contact **212** such that they move together in the second plane.

[0046] As disclosed by Hill, "In operation, when a magnetic flux is applied along the magnetic flux path it serves to align the magnetic element with the line and generate a force that draws the magnetic element toward the line." See *e.g.*, Hill: Col. 5, line 65 to Col. 6, line 1, and FIG. 1. Because tether **214** rigidly couples magnetic element **206** and electrical contact **212**, the motion of magnetic element **206** moves electrical contact **212** (through tether **214**) into physical contact with electrical lines **216** and **218**. The physical contact electrically shorts electrical lines **216** and **218** and enables the flow of current **120**.

[0047] Since the motion of electrical contact **212** is in a plane parallel to substrate **224**, relay **200** overcomes some of the disadvantages discussed above, vis-à-vis relay **100**. Specifically, the operating characteristics of relay 200 are determined primarily by photolithography.

[0048] Relay **200** also suffers from several disadvantages. First, as disclosed by Hill, the magnetic flux path embodied by magnetic elements **202** and **204** needs to be aligned with an externally applied magnetic field in order to enable reasonably efficient coupling between the magnetic field and magnetic elements **202** and **204**. The need for good alignment arises from the small cross-section of magnetic elements **202** and **204**, which limits the coupling efficiency of the elements to an applied magnetic field. As a result, it is necessary to provide a large magnetic field to ensure that enough magnetic force is generated at the actuator.

[0049] The need to provide a high magnetic field, in turn, makes it difficult to integrate a suitable planar coil with the structure of relay **200**. The challenge arises from the fact that an electromagnetic coil capable of generating a large magnetic field with sufficiently high quality factor would require an excessive amount of chip area.

[0050] It is of note that in those embodiments disclosed by Hill wherein a coil is shown, the coil is depicted as external to the relay. Further, it is arranged to provide a magnetic field that is oriented perpendicular to the substrate through magnetic poles are formed on the top and bottom surfaces of a multi-substrate stack. These pole pieces direct the externally generated magnetic field perpendicular to the substrate stack and induce motion of a magnetically actuated electrical-contact element in a direction that is also perpendicular to each of the substrates (see *e.g.*, Hill: Col. 8, line 59 to Col. 9, line 5, and FIG. 6). Such embodiments, of course, exhibit the same disadvantages described above, vis-à-vis relay **100**.

[0051] In contrast to micro-relays of the prior art, the present invention provides a relay comprising: (1) at least one integrated coil for generating a magnetic field; (2) a magnetic circuit, magnetically coupled to the coil(s), wherein the magnetic circuit efficiently channels the generated magnetic field through a magnetically actuated electrical switch; and (3) an electrical switch having a moving element that moves in a direction parallel to the substrate. As a result, embodiments of the present invention avoid the disadvantages inherent to a switch whose moving element moves perpendicularly to its substrate, yet also include a practical integrated planar coil suitable for actuating the switch.

[0052] Advances in microfabrication technology have led to the development of planar processing techniques that enable the fabrication of structures with significant thickness relative to their lateral dimensions. This realm of process technology has been coined "high aspect-ratio" processing to indicate the substantial dimensions that may be accommodated normal to the process substrate surface. High aspect-ratio processing has enabled, for example, the development of laterally actuated micro-relays. Further, due to the advent of high aspect-ratio processing, a movable magnetic element may be now rendered with sufficient cross sectional area relative to the length of the magnetic circuit to enable relatively low-loss coupling between a source of magnetic field and the working gap.

[0053] Vertically integrated, high aspect-ratio devices are especially attractive for use in applications involving relay arrays, where extreme miniaturization becomes even more important. Use of relays in automated test equipment and telecommunication applications, for example, are particularly concerned with the footprint and height consumed by the relay on a circuit board. Since batch or wafer based fabrication costs relate directly to the device area a vertically integrated relay with smaller footprint also has a cost advantage.

[0054] FIG. 3 depicts a simplified cross-sectional schematic drawing of a micro-relay in accordance with an illustrative embodiment of the present invention. Relay **300** comprises electromagnetic module **302**, actuator module **304**, coil **306**, magnetic cores **308** and **310**, cap **314**, and switch **316**.

[0055] Magnetic circuit **312** comprises two magnetic cores – magnetic core **308** and magnetic core **310**. Each magnetic core comprises ferromagnetic elements that are formed in each of electromagnetic module **302** and actuator module **304**. These ferromagnetic elements are mated in relay **300** such that they are magnetically coupled to form the magnetic cores and magnetic circuit **312**. Further, portions of each of magnetic core **308** and magnetic core **310** collectively define switch **316**. As described below, and with respect to FIGS. 7A and 7B, switch **316** comprises a moving contact that is enabled for motion only in a plane parallel to its underlying substrate. The magnetic circuit enables actuation of the switch using a weaker generated magnetic field. As a result, the integrated planar coil requires fewer turns so that the coil can be formed in a practical amount of chip area.

[0056] In addition, the illustrative embodiment comprises a plurality of planar coils, which work in concert to collectively generate the magnetic field. The planar coils are arranged such that a magnetic field generated by one coil is augmented by the rest of the coils. As a result, the plurality of coils collectively generates a significantly stronger magnetic field than possible for a practical single coil. By using a plurality of coils, the design parameters for each coil (*e.g.*, number of turns, current carrying capability, *etc.*) are relaxed, which makes them more easily integrated in relay **300**.

[0057] It is an aspect of the present invention that the coils are formed on different substrate than the magnetically actuated switch. Once formed, the different substrates are bonded to form a fully integrated device. In the illustrative embodiment, four coils **306** are formed on electromagnetic module **302**. The coils are arranged in two coil pairs, wherein each coil pair surrounds one of the magnetic cores. As a result, the magnetic field generated by each coil is efficiently coupled into its respective core.

[0058] In similar fashion, switch **316** is formed on separate actuator module **304**. In order to facilitate their integration in relay **300**, the magnetic and electrical vias of each substrate are arranged in a common interface that ensures their proper mating when the substrates are attached.

[0059] This common interface for the magnetic and electrical vias of the electromagnetic module provides embodiments of the present invention with significant advantages with respect to design, manufacturing, and inventory control. For example, a "generic" electromagnetic module can be volume-produced with lower cost. Further, a generic electromagnetic module can be used to actuate any of a family of actuator modules through the common interface.

[0060] The common interface also enables the formation of multiple, stackable electromagnetic modules that can be assembled together to cooperatively provide any practical magnitude of magnetic field strength. As a result, embodiments of the present invention offer greater design flexibility and reduce the cost of manufacture.

[0061] FIG. 4 depicts operations of a method for forming a micro-relay in accordance with the illustrative embodiment of the present invention. Method **400** begins with operation **401**, wherein electromagnetic module **302** is provided.

[0062] FIGS. 5A and 5B depict schematic drawings of a top view and cross-sectional view through line a-a, respectively, of electromagnetic module **302**. Electromagnetic module **302** comprises elements for generating and augmenting a magnetic field, as well as elements for efficiently channeling the generated magnetic field to an actuator module. Electromagnetic module **302** further comprises a plurality of contact pads for enabling electrical connectivity and surface mounting of the substrate.

[0063] Electromagnetic module **302** comprises substrate **502**, coils **306-1** through **306-4**, contact pads **506**, **508**, **510**, and **512**, magnetic vias **514** and **516**, electrical vias **518**, **520**, **522**, and **524**, shield **526**, and magnetic pads **530** and **532**. It should be noted that, for clarity, FIG. 5B depicts a cross-sectional view through the center of representational coils, rather than a view of coils **306-1** through **306-4** through line a-a.

[0064] FIG. 6 depicts sub-operations suitable for use in operation **401**, wherein electromagnetic module **302** is formed in accordance with the illustrative embodiment of the present invention. Operation **401** begins with sub-operation **601**, wherein through-wafer electrical vias **518**, **520**, **522**, and **524** are formed in substrate **502**.

[0065] Substrate **502** is a substrate suitable for supporting the microfabrication of one or more electrically conductive coils. In the illustrative embodiment, substrate **502** is an alumina substrate; however, it will be clear to one skilled in the art, after reading this Specification, how to specify, make, and use alternative embodiments of the present invention wherein substrate **502** is any suitable substrate. For the purposes of this Specification, including appended claims, "**substrate**" is defined as a substrate that is suitable for planar processing fabrication operations such as those typically employed in MEMS fabrication, nanotechnology fabrication, or integrated circuit fabrication. Examples of suitable substrate materials include, without limitation, silicon, germanium, compound semiconductors, semiconductor-on-insulator layer structures, glass, ceramics, alumina, *etc*., and combinations thereof.

[0066] Electrical vias **518**, **520**, **522**, and **524** are formed in conventional fashion, wherein holes are formed through substrate **502** are then filled with electrically conductive material, such as, for example, gold, aluminum, doped polysilicon, and tungsten. The holes can be formed using any suitable fabrication technique, such as DRIE, sand blasting, water drilling, laser-assisted etching, and the like. In some embodiments, such as those wherein substrate **502** is a cast ceramic substrate, the holes can be formed during formation of the substrate.

[0067] The holes are filled with electrically conductive material using a conventional technique, such as electroplating, chemical vapor deposition, and the like. In some embodiments substrate **502** comprises an electrically conductive material or a semi-conductor. In such embodiments, an insulating layer is first deposited on the sidewalls of the holes to electrically isolate each electrical via from substrate **502**. It will be clear to one skilled in the art how to specify, make, and use electrical vias **518**, **520**, **522**, and **524**.

[0068] At sub-operation **602**, through-wafer magnetic vias **514** and **516** are formed in substrate **502**. Formation of magnetic vias **514** and **516** is analogous to the formation of the electrical vias described above; however, magnetic vias **514** are formed with ferromagnetic material and are therefore capable of channeling magnetic flux between surfaces **540** and **542** of substrate **502** as part of magnetic circuit **312**, as described below and with respect to FIG. 9.

[0069] At sub-operation **603**, coils **306-1** through **306-4**, inter-coil vias **546** and **548**, and interconnect **528** are formed. It should be noted that in embodiments wherein substrate **502** is an electrically conductive or a semi-conducting substrate, surface **540** comprises an electrically insulating layer upon which the coils are disposed.

[0070] Each of coils **306-1** through **306-4** (collectively referred to as coils **306**) is a substantially planar spiral of electrically conductive material that generates a magnetic field when energized by a current. Each of coils **306** lies in a plane that is substantially parallel to plane **534**, which is defined by substrate **502**. Specifically, coils **306-1** and **306-4** are coplanar and lie in plane **536** and coils **306-2** and **306-3** are coplanar and lie in plane **538**. In some embodiments, each of coils **306** lies in a different plane, wherein each of these planes is substantially parallel to one another. Although the illustrative embodiment comprises four coils **306**, it will be clear to one skilled in the art, after reading this Specification, how to specify, make, and use alternative embodiments of the present invention that comprise any practical number of coils that is less than or greater than four.

[0071] When energized with current, each of coils **306** generates a magnetic field that is oriented in a direction based on the direction of its flow through that coil. In the illustrative embodiment, coils **306-1** and **306-2** are dimensioned and arranged such that they are substantially concentric and the magnetic flux generated by each is directed in the positive z-direction at planes **536** and **538**, respectively. As a result, the magnetic field generated by coil **306-1** can be augmented by the magnetic field generated by coil **306-2** (or visa-versa). Coils **306-3** and **306-4** are dimensioned and arranged such that they are substantially concentric and the magnetic flux generated by each is directed in the negative z-direction at planes **538** and **536**, respectively. As a result, the magnetic field generated by coil **306-3** is augmented by the magnetic field generated by coil **306-4** (or visa-versa). Further, the magnetic fields generated by coils **306-3** and **306-4** augment the combined magnetic field generated by coils **306-1** and **306-2** through magnetic circuit **312**, as described below and with respect to FIG. 9. It should be noted that the direction of current flow through the coils and the relative orientation of the coils are matters of design choice. Further, the physical layout of coils **306**, such as number of turns, cross-section of the coil trace, type of electrically conductive material, are also matters of design choice and it will be clear to one skilled in the art, after reading this Specification, how to specify, make, and use coils **306**.

[0072] Coils **306-1** through **306-4**, inter-coil vias **546** and **548**, and interconnect **528** are formed using a series of dielectric layer depositions, dielectric etching, metal depositions, and electroplating. Coils **306-1** and **306-4** are formed on surface **540** of substrate **502** by operations including: (1) depositing a first layer of electrically conductive material on surface **540**; (2) forming a mask layer on the first layer, wherein the mask layer includes openings in the desired shapes of coils **306-1** and **306-4**; (3) immersing the substrate in an electroplating bath, wherein electrically conductive material is selectively deposited in the open areas of the mask layer; and (4) removing the mask layer and non-plated regions of the first layer. After their formation, coils **306-1** and **306-4** are electrically connected to electrical vias **518** and **520**, respectively, but are not electrically connected to one another. It should be noted that electroplating represents only one suitable technique for forming coils **306** and that one skilled in the art, after reading this Specification, will be able to specify and use any suitable alternative technique to form coils **306** in accordance with the present invention.

[0073] After the formation of coils **306-1** and **306-4**, they are encapsulated by the deposition of dielectric layer **504**. Dielectric layer **504** is planarized using, for example, chemical-mechanical polishing. Inter-coil vias **546** and **548** are formed through dielectric layer **504** such that they are electrically connected to coils **306-1** and **306-2**, respectively.

[0074] Coil **306-2**, coil **306-3**, and interconnect **528** are then formed on dielectric layer **504** such that coils **306-2** and **306-3** are electrically connected to inter-coil vias **546** and **548** and coils **306-2** and **306-3** are electrically connected through interconnect **528**. Upon completion, electrical via **518**, coils **306**, inter-coil vias **546** and **548**, interconnect **528**, and electrical via **520** collectively define a continuous electrically conductive path.

[0075] At sub-operation **604**, magnetic vias **514** and **516** are extended vertically and shield **526** is formed using conventional photolithography and electroplating operations. When relay **300** is fully assembled, shield **526** forms a portion of a barrier for protecting relay **300** from the effects of stray magnetic fields.

[0076] Coils **306-1** and **306-2** are substantially concentric and surround magnetic via **514** in planes **536** and **538**, respectively. Coils **306-3** and **306-4** are concentric and surround magnetic via **516** in planes **536** and **538**, respectively. The vertical extension of magnetic vias **514** and **516** enables their physically contact with magnetic vias included in actuator module **304** as part of magnetic circuit **312**, as described below and with respect to FIGS. 7-10.

[0077] At sub-operation **605**, electrical vias **522** and **524** are extended vertically by patterning dielectric **504** and electroplating electrically conductive material. The vertical extension of electrical vias **522** and **524** enable subsequent electrical contact between them and electrical vias **708** and **710** of actuator module **304**.

[0078] At sub-operation **606**, electroplating is used to form electrically conductive contact pads **506**, **508**, **510**, and **512** on surface **542**. The contact pads are formed such that contact pad **506** is electrically connected to electrical via **518**, contact pad **508** is electrically connected to electrical via **520**, contact pad **510** is electrically connected to electrical via **522**, and contact pad **512** is electrically connected to electrical via **524**. As a result, electromagnetic module **302** is suitable for surface mount attachment.

[0079] At sub-operation **607**, magnetic pads **530** and **532** are formed, via electroplating, on surface **542**. Each of magnetic pads **530** and **532** comprises ferromagnetic material and can channel a magnetic field. Upon completion of sub-operation **607**, magnetic via **514** is physically connected to magnetic pad **530** and magnetic via **516** is physically connected to magnetic pad **532**. It should be noted that magnetic pads **530** and **532** are physically separated by armature gap **g1**. Armature gap **g1** electrically isolates magnetic pads **530** and **532** from one another and avoids development of an undesirable shunt for electric current during operation of relay **300**. Armature gap **g1** is typically made as small as possible, however, to ensure a low-reluctance path between magnetic pads **530** and **532**.

[0080] Although in the illustrative embodiment, electroplating is used to form elements included in electromagnetic module **302**, it will be clear to one skilled in the art, after reading this Specification, how to specify, make, and use coils and/or other elements that are formed using other planar fabrication techniques, such as photolithography, electroplating, metal lift-off, subtractive layer patterning (*e.g.*, etching, ablation, sand blasting, *etc.*), and the like.

[0081] At operation **402**, actuator module **304** is provided.

[0082] FIGS. 7A and 7B depict schematic drawings of a top view and cross-sectional view through line b-b, respectively, of actuator module **304**. Actuator module **304** comprises substrate **702**, switch **316**, anchors **712** and **714**, magnetic vias **704** and **706**, electrical vias **708** and **710**, seal ring **718**, and shield **716**.

[0083] FIG. 8 depicts sub-operations suitable for use in operation **402**, wherein actuator module **304** is formed in accordance with the illustrative embodiment of the present invention. Operation **402** begins with sub-operation **801**, wherein through-wafer magnetic vias **704** and **706** are formed in substrate **502**.

[0084] Substrate **702** is a substrate suitable for supporting the formation of switch **316**. Substrate **702** defines plane **732**. Substrate **702** is analogous to substrate **502**.

[0085] Magnetic vias **704** and **706** are through-wafer magnetic vias that are analogous to magnetic vias **514** and **516**. Magnetic vias **704** and **706** are physically connected and magnetically coupled to anchors **712** and **714**, respectively.

[0086] At sub-operation **802**, through-wafer electrical vias **708** and **710** are formed in substrate **702**. Electrical vias **708** and **710** are through-wafer electrical vias that are analogous to electrical vias **514**, **518**, **520**, and **524**.

[0087] Magnetic vias **704** and **706** and electrical vias **708** and **710** are arranged in the same arrangement as magnetic vias **514** and **516** and electrical vias **522** and **524** of electromagnetic module **302**. This matching arrangement provides the "common interface," referred to above, between electromagnetic module **302** and actuator module **304**. Once the substrates are aligned and bonded, therefore, magnetic vias **704** and **706** and magnetic vias **514** and **516** are magnetically coupled and electrical vias **708** and **710** and electrical vias **522** and **524** are electrically connected. In some embodiments, magnetic vias **704** and **706** and magnetic vias **514** and **516** are in physical contact when substrates **302** and **304** are aligned and bonded.

[0088] At sub-operation **803**, electroplating is again used to form anchors **712** and **714** disposed on surface **720** of substrate **702**.

[0089] Each of anchors **712** and **714** comprises a material that is both ferromagnetic and electrically conductive. Anchor **712** and electrical via **708** are electrically connected. Anchor **712** is also physically and magnetically coupled with magnetic via **704**. In similar fashion anchor **714** and electrical via **710** are electrically connected and anchor **714** and magnetic via **706** are magnetically coupled.

[0090] Element **724** is also formed during the formation of anchor **712**. In order to enable operation of relay **300**, however, sacrificial layer **740** is formed such that it interposes element **724** and surface **720**. One skilled in the art will recognize that sacrificial layer **740** can comprise any material that can be selectively removed from electromagnetic module **304**. The choice of material for use as sacrificial layer **740** depends on the material from which anchors **712** and **714** and element **724** are formed. It will be clear to one skilled in the art, after reading this Specification, how to specify, make, and use sacrificial layer **740**.

[0091] Element **724** is a cantilever beam disposed from anchor **712**. After release of element **724** from the substrate, end **730** of element **724** is rigidly connected at anchor **712**. End **728** of element **724**, however, is free to selectively move within plane **734**, which is substantially parallel to plane **732**. End **728** comprises electrical contact **722**. In other words, element **724** is dimensioned and arranged to enable motion of contact **722** within plane **734** but inhibit motion of contact **722** out of plane **734**.

[0092] In some alternative embodiments, element **724** is a mechanical element other than a cantilever beam but still enables motion of contact **722** within plane **734**. Element **724** comprises a material that is both ferromagnetic and electrically conductive. As a result: (1) electrical via **708**, anchor **712**, element **724**, and electrical contact **722** collectively define a continuous electrically conductive path; and (2) magnetic via **704**, anchor **712**, element **724**, and electrical contact **722** collectively define a continuous ferromagnetic path.

[0093] Anchor **714** comprises electrical contact **726**. Electrical contact **722**, element **724**, and contact **726** collectively define magnetically actuated switch **316**. Initially, electrical contacts **722** and **726** are separated by working gap, **g2**, when switch **316** is in its non-actuated state.

[0094] In some embodiments, one or both of electrical contacts **722** and **726** comprise projections for concentrating contact force and reducing electrical contact resistance between them. In some embodiments, one or both of electrical contacts **722** and **726** comprise a low resistivity material, such as gold, for reducing electrical contact resistance between them.

[0095] At sub-operation **804**, shield **716** is formed on surface **720**. Shield **716** is analogous to shield **526**. Shield **716** is dimensioned and arranged to mechanically bond with cap **314** when relay **300** is assembled. When relay **300** is fully assembled, shield **716** forms a portion of a barrier for protecting relay **300** from the effects of stray magnetic fields.

[0096] At sub-operation **805**, seal ring **718** is formed on surface **736**. Seal ring **718** is a thin metal layer that provides a suitable bonding surface for shield **526** during assembly of electromagnetic module **302** and actuator module **304**.

[0097] At sub-operation **806**, element **724** is released from surface **720** by selective removal of sacrificial layer **740**. Since element **724** selectively moves in plane **734**, its mechanical behavior is based, not on its dimension in the z-direction, but on its width in the y-direction. As a result, the mechanical behavior of element **724** is lithographically determined during the formation of the mask layer used to define the element during the electroplating process. Photolithography is an extremely well-controlled and repeatable process. Thus, operational characteristics can be tightly controlled and consistent across all relays of the same design. Furthermore, photolithography enables the definition of element **724** with extremely tight dimensional tolerances. This enables the design of a relay with an extremely small working gap, **g2**, and, therefore, a low actuation magnetic field requirement.

[0098] At operation **403**, cap **314** is provided. Cap **314** forms a portion of a shield for protecting switch **316** and coils **306** from the effects of stray magnetic fields. Cap **314** is dimensioned and arranged to mechanically bond with shield **716** when relay **300** is fully assembled.

[0099] At operation **404**, electromagnetic module **302**, actuator module **304**, and cap **314** are assembled to form relay **300**. During assembly of relay **300**, electromagnetic module **302** and actuator module **304** are aligned so that magnetic vias **514** and **516** are in physical contact with magnetic vias **704** and **706**, respectively. In addition, the substrates are aligned so that electrical vias **522** and **524** make electrical contact with electrical vias **708** and **710**, respectively. Once they are aligned as desired, electromagnetic module **302**, actuator module **304**, and cap **314** are bonded to one another using conventional bonding techniques.

[0100] FIG. 9 depicts a cross-sectional view of fully assembled relay **300** in accordance with the illustrative embodiment of the present invention.

[0101] After assembly of relay **300**, magnetic pad **530**, magnetic vias **514** and **704**, anchor **712**, and element **724** collectively define magnetic core **308**. Magnetic core **308** is surrounded by coils **306-1** and **306-2** in planes **536** and **538**, respectively. As a result, the magnetic fields generated by each of coils **306-1** and **306-2** are efficiently coupled into magnetic core **308**.

[0102] In similar fashion, magnetic pad **532**, magnetic vias **516** and **706**, and anchor **714** collectively define magnetic core **310**. Magnetic core **310** is surrounded by coils **306-4** and **306-3** in planes **536** and **538**, respectively. As a result, the magnetic fields generated by each of coils **306-3** and **306-4** are efficiently coupled into magnetic core **310**.

[0103] Magnetic cores **308** and **310** collectively define magnetic circuit **312**, which is depicted in FIG. 10. Magnetic circuit **312** is referred to herein as a "closed magnetic circuit." For the purposes of this Specification, including the appended claims, the term "**closed magnetic circuit**" is defined as a circuit of ferromagnetic material that enables the circulation of a magnetic field through a closed path. In other words, a closed magnetic circuit has a substantially ferromagnetic return path that channels a magnetic field back to its source. A closed magnetic circuit can comprise one or more air gaps; however, the air gaps are sufficiently small that they enable efficient magnetic coupling across them. Magnetic circuit **312** channels the magnetic field collectively generated by coils **306** through switch **316**, including working gap **g2**. As discussed above, and with respect to FIGS 5A and 5B, the magnetic fields generated by coils **306-1** and **306-2** are directed in the positive z-direction at planes **536** and **538**, respectively and the magnetic fields generated by coils **306-3** and **306-4** are directed in the negative z-direction at planes **538** and **536**, respectively. These magnetic fields are channeled by magnetic circuit **312** in a generally clockwise direction (as depicted in FIG. 10).

[0104] Once relay **300** is assembled, electrical via **708**, electrical via **522**, and contact pad **510** collectively define terminal **738**, which is electrically connected to magnetic core **308**. In similar fashion, electrical via **710**, electrical via **524**, and contact pad **512** collectively define terminal **740**, which is electrically connected to magnetic core **310**. It should be noted that in some embodiments, switch **316** is disposed on surface **736** of actuator module **304**. In such embodiments, magnetic vias **704** and **706**, electrical vias **708 and 710**, and cap **314** are not required. Further, in some embodiments, magnetic vias **514** and **516** are in close proximity to, but not in physical contact with, magnetic vias **704** and **706**.

[0105] In operation, a first current is injected at contact pad **506** and flows from contact pad **506** to contact **508** through electrical vias **518** and **520** and coils **306**. This first current energizes each of coils **306**. In response to the flow of the first current, coil **306-1** generates a magnetic field that is augmented by coils **306-2** through **306-4** and channeled by magnetic circuit **312** through electrical contacts **722** and **726** and working gap **g2**. As a result, free end **728** of element **316** is attracted toward electrical contact **726** to force electrical contacts **722** and **726** into physical and electrical contact. It should be noted that the mechanical design of element **724** and the size of working gap **g2** determine the amount of force required to actuator switch **316**.

[0106] By virtue of the electrical connection between electrical contacts **726** and **722**, a flow of a second current between contact pads **510** and **512** (through electrical vias **522**, **708**, **710**, and **524**) is enabled.

[0107] In some embodiments, electrical contacts **722** and **726** are initially in physical and electrical contact and the flow of the first current induces a separation of electrical contacts **722** and **726** to disable the flow of the second current.

[0108] FIG. 11 depicts a schematic diagram of a cross-sectional view of a micro-relay in accordance with a first alternative embodiment of the present invention. Relay **1100** comprises electromagnetic modules **1102**, **1104**, and **1106**, actuator module **304**, and cap **314**.

[0109] Each of electromagnetic modules **1102**, **1104**, and **1106** is analogous to electromagnet substrate **302**; however, each comprises only two coils for generating a magnetic field.

[0110] Electromagnetic module **1102** comprises substrate **502-1**, contact pads **506**, **508**, **510**, and **512**, coils **306-1** and **306-2**, electrical vias **522**, and magnetic vias **514**.

[0111] Electromagnetic module **1104** comprises substrate **502-2**, coils **306-3** and **306-4**, electrical vias **522**, and magnetic vias **514**. In some embodiments, electromagnetic module **1104** is flipped about the x-axis such that coils **306-3** and **306-4** are disposed on the bottom surface of substrate **502-2**.

[0112] Electromagnetic module **1106** comprises substrate **502-3**, coils **306-5** and **306-6**, electrical vias **522**, and magnetic vias **514**. In some embodiments, electromagnetic module **1106** is flipped about the x-axis such that coils **306-5** and **306-6** are disposed on the bottom surface of substrate **502-3**.

[0113] Electromagnetic modules **1102**, **1104**, and **1106** are aligned and bonded such that their magnetic vias are magnetically coupled to form a closed magnetic circuit that is analogous to magnetic circuit **312**. In addition, coils **306** are electrically connected in series via electrical vias **518** and **1108**, and interconnect **528** so that coils **306-3** and **306-4** form a continuous path for current.

[0114] Although the first alternative embodiment comprises three electromagnetic modules, it will be clear to one skilled in the art, after reading this Specification, how to specify, make, and use alternative embodiments of the present invention that comprise any practical number of electromagnetic modules.

[0115] The ability to stack any number of electromagnetic modules together enables wide design latitude for actuator design, lower inventory costs, and reduced manufacturing costs for embodiments of the present invention as compared to the prior art.

[0116] It is to be understood that the disclosure teaches just one example of the illustrative embodiment and that many variations of the invention can easily be devised by those skilled in the art after reading this disclosure and that the scope of the present invention is to be determined by the following claims.

What is claimed is:

1. An apparatus comprising:

a first substrate comprising a first coil for generating a magnetic field, wherein the coil is substantially planar and lies in a first plane, and wherein the first coil and the first substrate are monolithically integrated; and

a second substrate comprising an electrical switch that comprises a first electrical contact and a second electrical contact, wherein the first electrical contact is moved by the magnetic field, and wherein the electrical switch and the second substrate are monolithically integrated, and further wherein the first electrical contact moves selectively in a second plane that is substantially parallel to the first plane.

2. The apparatus of claim 1 wherein the first substrate further comprises a second coil for augmenting the magnetic field, wherein the second coil is substantially planar and lies in the first plane, and wherein the second coil and the first substrate are monolithically integrated.

3. The apparatus of claim 1 wherein the first substrate further comprises a second coil for augmenting the magnetic field, wherein the second coil is substantially planar and lies in a third plane that is substantially parallel to the first plane, and wherein the first coil and second coil are substantially concentric, and further wherein the second coil and the first substrate are monolithically integrated.

4. The apparatus of claim 1 wherein the first substrate further comprises:

a third electrical contact; and

a fourth electrical contact;

wherein the first substrate has a first surface and a second surface, and wherein the first coil is proximal to the first surface and distal to the second surface, and further wherein the third electrical contact and fourth electrical contact are proximal to the second surface and distal to the first surface; and

wherein the first coil generates the magnetic field based on a first current that flows between the third electrical contact and the fourth electrical contact.

5. The apparatus of claim 4 wherein the first substrate further comprises:

a fifth electrical contact, wherein the first electrical contact and fifth electrical contact are electrically coupled; and

a sixth electrical contact, wherein the second electrical contact and the sixth electrical contact are electrically coupled;

wherein the fifth electrical contact and sixth electrical contact are proximal to the second surface and distal to the first surface; and

wherein the magnetic field moves the first electrical contact into physical contact with the second electrical contact and enables the flow of a second current between the fifth electrical contact and the sixth electrical contact.

6. The apparatus of claim 5 further comprising a closed magnetic circuit for channeling the magnetic field through the electrical switch, wherein the closed magnetic circuit comprises:

a first magnetic core, wherein the first magnetic core comprises the first electrical contact; and

a second magnetic core, and wherein the second magnetic core comprises the second electrical contact.

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7. An apparatus comprising:

a first coil for generating a magnetic field, wherein the first coil is substantially planar and lies in a first plane;

a first magnetic core for channeling the magnetic field, wherein the first magnetic core comprises a first electrical terminal and a first electrical contact that is movable, and wherein the first coil surrounds the first magnetic core in the first plane;

a second coil for augmenting the magnetic field, wherein the first coil is substantially planar and lies in a second plane; and

a second magnetic core for channeling the magnetic field, wherein the second magnetic core comprises a second electrical terminal and a second electrical contact, and wherein the second coil surrounds the second magnetic core in the second plane;

wherein the first electrical contact and the second electrical contact collectively define a magnetically actuated switch for controlling the flow of a first current between the first electrical terminal and the second electrical terminal.

8. The apparatus of claim 7 wherein the first plane and the second plane are substantially the same plane.

9. The apparatus of claim 7 wherein the first coil and the second coil are electrically connected in series.

10. The apparatus of claim 7 wherein the first electrical contact is movable in a third plane that is substantially parallel to the first plane.

11. The apparatus of claim 7 further comprising a first substrate and a second substrate, wherein the first substrate, the first coil, and the second coil are monolithically integrated, and wherein the second substrate, the first electrical contact, and the second electrical contact are monolithically integrated.

12. An apparatus comprising:

(1) a first substrate that defines a first plane, wherein the first substrate comprises a plurality of coils for collectively generating a magnetic field, and wherein each of the coils is substantially planar and parallel to the first plane, and further wherein the first substrate and the plurality of coils are monolithically integrated, and

(2) a second substrate comprising an electrical switch that comprises a first electrical contact and a second electrical contact, wherein the first electrical contact is dimensioned and arranged to move selectively in a second plane that is substantially parallel to the first plane, and further wherein the second substrate, the first electrical contact, and second electrical contact are monolithically integrated;

wherein the magnetic field moves the first electrical contact in the second plane to actuate the electrical switch.

13. The apparatus of claim 12 further comprising a closed magnetic circuit for channeling the magnetic field through the electrical switch, wherein the closed magnetic circuit comprises:

(3) a first magnetic core comprising;

(a) a first via that is through the first substrate, wherein the first via and a first coil of the plurality of coils are concentric;

(b) a second via that is through the second substrate; and

(c) a first anchor comprising a first member that is movable in the second plane, wherein the first member comprises the first electrical contact, and wherein the second substrate, the first anchor, and the first member are monolithically integrated;

wherein each of the first via, second via, and first anchor comprises ferromagnetic material; and

(4) a second magnetic core comprising;

(a) a third via that is through the first substrate, wherein the third via and a second coil of the plurality of coils are concentric;

(b) a fourth via that is through the second substrate; and

(c) a second anchor comprising the second electrical contact, wherein the second substrate and the second anchor are monolithically integrated;

wherein each of the third via, fourth via, and second anchor comprises ferromagnetic material.

14. The apparatus of claim 13 wherein the first substrate further comprises:

(3) a third electrical contact;

(4) a fourth electrical contact, wherein the third electrical contact, each of the plurality of coils, and the fourth electrical contact are electrically coupled;

(5) a fifth electrical contact, wherein the fifth electrical contact and the first electrical contact are electrically coupled; and

(6) a sixth electrical contact, wherein the sixth electrical contact and the second electrical contact are electrically coupled;

wherein the first substrate comprises a first surface and a second surface, and wherein each of the plurality of coils is proximal to the first surface and distal to the second surface;

wherein the third electrical contact, fourth electrical contact, fifth electrical contact, and sixth electrical contact are proximal to the second surface and distal to the first surface; and wherein the magnetic field electrically couples the first electrical contact and second electrical contact and enables the flow of a current between the fifth electrical contact and the sixth electrical contact.

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15. A method comprising:

providing a first substrate comprising a first coil for generating a magnetic field, wherein the first coil is substantially planar and lies in a first plane;

providing a second substrate comprising an electrical switch that is a magnetically actuated switch, wherein the electrical switch comprises a first electrical contact and a second electrical contact, and wherein the first electrical contact is movable selectively in a second plane; and

arranging the first substrate and second substrate in a first arrangement wherein the second plane is substantially parallel to the first plane; and

enabling the coupling of the magnetic field and the electrical switch.

16. The method of claim 15 further wherein the coupling of the magnetic field and electrical switch is enabled by operations comprising:

providing a first magnetic core, wherein the first coil surrounds the first magnetic core in the first plane; and

providing a second magnetic core, wherein the first magnetic core and second magnetic core collectively define a closed magnetic circuit;

wherein the first magnetic core and second magnetic core are dimensioned and arranged to collectively channel the magnetic field through the electrical switch.

17. The method of claim 16:

wherein the first magnetic core is provided by operations comprising:

forming a first via through the first substrate;

forming a second via through the second substrate; and

forming a first anchor on the second substrate, wherein the first anchor comprises a first member that is movable in the second plane, and wherein the first member comprises the first electrical contact;

wherein each of the first via, second via, and first anchor comprises ferromagnetic material; and

wherein the second magnetic core is provided by operations comprising:

forming a third via that is through the first substrate;

forming a fourth via that is through the second substrate; and

forming a second anchor on the second substrate, wherein the second anchor comprises the second electrical contact;

wherein each of the third via, fourth via, and second anchor comprises ferromagnetic material;

wherein the first arrangement enables magnetic coupling between the first and second via and between the third and fourth via.

18. The method of claim 17 further comprising:

providing a third electrical contact;

providing a fourth electrical contact, wherein the third electrical contact, first coil, and fourth electrical contact are electrically coupled;

providing a fifth electrical contact that is electrically coupled with the first electrical contact; and

providing a sixth electrical contact that is electrically coupled with the second electrical contact;

wherein the first substrate comprises the third electrical contact, fourth electrical contact, fifth electrical contact, and sixth electrical contact, and wherein the first substrate comprises a first surface and a second surface, and wherein the first coil is proximal to the first surface and distal to the second surface, and further wherein each of the third electrical contact, fourth electrical contact, fifth electrical contact, and sixth electrical contact is proximal to the second surface and distal to the first surface.

19. The method of claim 15 further comprising providing a second coil for augmenting the magnetic field, wherein the first substrate comprises the second coil, and wherein the second coil is substantially planar and lies in the first plane.

20. The method of claim 15 further comprising providing a second coil for augmenting the magnetic field, wherein the first substrate comprises the second coil, and wherein the second coil is substantially planar and lies in a third plane that is substantially parallel to the first plane, and further wherein the first coil and second coil are substantially concentric.

AMENDED CLAIMS
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1. An apparatus comprising:

a first substrate comprising a first coil for generating a magnetic field, wherein the coil is substantially planar and lies in a first plane, and wherein the first coil and the first substrate are monolithically integrated; and

a second substrate comprising an electrical switch that comprises a first electrical contact and a second electrical contact, wherein the first electrical contact is moved by the magnetic field, and wherein the electrical switch and the second substrate are monolithically integrated, and further wherein the first electrical contact moves selectively in a second plane that is substantially parallel to the first plane.

2. The apparatus of claim 1 wherein the first substrate further comprises a second coil for augmenting the magnetic field, wherein the second coil is substantially planar and lies in the first plane, and wherein the second coil and the first substrate are monolithically integrated.

3. The apparatus of claim 1 wherein the first substrate further comprises a second coil for augmenting the magnetic field, wherein the second coil is substantially planar and lies in a third plane that is substantially parallel to the first plane, and wherein the first coil and second coil are substantially concentric, and further wherein the second coil and the first substrate are monolithically integrated.

4. The apparatus of claim 1 wherein the first substrate further comprises:

a third electrical contact; and

a fourth electrical contact;

wherein the first substrate has a first surface and a second surface, and wherein the first coil is proximal to the first surface and distal to the second surface, and further wherein the third electrical contact and fourth electrical contact are proximal to the second surface and distal to the first surface; and

wherein the first coil generates the magnetic field based on a first current that flows between the third electrical contact and the fourth electrical contact.

5. The apparatus of claim 4 wherein the first substrate further comprises:

a fifth electrical contact, wherein the first electrical contact and fifth electrical contact are electrically coupled; and

a sixth electrical contact, wherein the second electrical contact and the sixth electrical contact are electrically coupled;

wherein the fifth electrical contact and sixth electrical contact are proximal to the second surface and distal to the first surface; and

wherein the magnetic field moves the first electrical contact into physical contact with the second electrical contact and enables the flow of a second current between the fifth electrical contact and the sixth electrical contact.

6. The apparatus of claim 5 further comprising a closed magnetic circuit for channeling the magnetic field through the electrical switch, wherein the closed magnetic circuit comprises:

a first magnetic core, wherein the first magnetic core comprises the first electrical contact; and

a second magnetic core, and wherein the second magnetic core comprises the second electrical contact.

7. The apparatus of claim 1 further comprising:

a first magnetic core for channeling the magnetic field, the first magnetic core comprising a first electrical terminal and the first electrical contact, wherein the first coil surrounds the first magnetic core in the first plane;

a second coil that is substantially planar and lying in a second plane, wherein the first coil and the second coil are dimensioned and arranged to collectively generate the magnetic field; and

a second magnetic core for channeling the magnetic field, the second magnetic core comprising a second electrical terminal and the second electrical contact, wherein the second coil surrounds the second magnetic core in the second plane;

wherein the electrical switch controls the flow of a first current between the first electrical terminal and the second electrical terminal.

8. The apparatus of claim 7 wherein the first plane and the second plane are substantially the same plane.

9. The apparatus of claim 1 further comprising a closed magnetic circuit for channeling the magnetic field through the electrical switch, wherein the closed magnetic circuit comprises:

a first magnetic core comprising;
  a first via that is through the first substrate, wherein the first via and the first coil are concentric;
  a second via that is through the second substrate; and
  a first anchor comprising a first member that moves selectively in the second plane, the first member comprising the first electrical contact;
  wherein the second substrate, the first anchor, and the first member are monolithically integrated, and wherein each of the first via, the second via, and the first anchor comprises ferromagnetic material; and
a second magnetic core comprising;
a third via that is through the first substrate;
a fourth via that is through the second substrate; and
a second anchor comprising the second electrical contact, wherein the second substrate and the second anchor are monolithically integrated;
wherein each of the third via, the fourth via, and second anchor comprises ferromagnetic material.

10. The apparatus of claim 9 further comprising a second coil, wherein the second coil is dimensioned and arranged to operate with the first coil to collectively generate the magnetic field, and wherein the first substrate comprises the second coil, and further wherein the third via and the second coil are concentric.

11. A method comprising:

providing a first substrate comprising a first coil for generating a magnetic field, wherein the first coil is substantially planar and lies in a first plane;

providing a second substrate comprising an electrical switch that is a magnetically actuated switch, wherein the electrical switch comprises a first electrical contact and a second electrical contact, and wherein the first electrical contact is movable selectively in a second plane; and

arranging the first substrate and second substrate in a first arrangement wherein the second plane is substantially parallel to the first plane; and

enabling the coupling of the magnetic field and the electrical switch.

12. The method of claim 11 further wherein the coupling of the magnetic field and electrical switch is enabled by operations comprising:

providing a first magnetic core, wherein the first coil surrounds the first magnetic core in the first plane; and

providing a second magnetic core, wherein the first magnetic core and second magnetic core collectively define a closed magnetic circuit;

wherein the first magnetic core and second magnetic core are dimensioned and arranged to collectively channel the magnetic field through the electrical switch.

13. The method of claim 12:

wherein the first magnetic core is provided by operations comprising:

forming a first via through the first substrate;

forming a second via through the second substrate; and

forming a first anchor on the second substrate, wherein the first anchor comprises a first member that is movable in the second plane, and wherein the first member comprises the first electrical contact;

wherein each of the first via, second via, and first anchor comprises ferromagnetic material; and

wherein the second magnetic core is provided by operations comprising:

forming a third via that is through the first substrate;

forming a fourth via that is through the second substrate; and

forming a second anchor on the second substrate, wherein the second anchor comprises the second electrical contact;

wherein each of the third via, fourth via, and second anchor comprises ferromagnetic material;

wherein the first arrangement enables magnetic coupling between the first and second via and between the third and fourth via.

14. The method of claim 13 further comprising:

providing a third electrical contact;

providing a fourth electrical contact, wherein the third electrical contact, first coil, and fourth electrical contact are electrically coupled;

providing a fifth electrical contact that is electrically coupled with the first electrical contact; and

providing a sixth electrical contact that is electrically coupled with the second electrical contact;

wherein the first substrate comprises the third electrical contact, fourth electrical contact, fifth electrical contact, and sixth electrical contact, and wherein the first substrate comprises a first surface and a second surface, and wherein the first coil is proximal to the first surface and distal to the second surface, and further wherein each of the third electrical contact, fourth electrical contact, fifth electrical contact, and sixth electrical contact is proximal to the second surface and distal to the first surface.

15. The method of claim 11 further comprising providing a second coil for augmenting the magnetic field, wherein the first substrate comprises the second coil, and wherein the second coil is substantially planar and lies in the first plane.

16. The method of claim 11 further comprising providing a second coil for augmenting the magnetic field, wherein the first substrate comprises the second coil, and wherein the second coil is substantially planar and lies in a third plane that is substantially parallel to the first plane, and further wherein the first coil and second coil are substantially concentric.

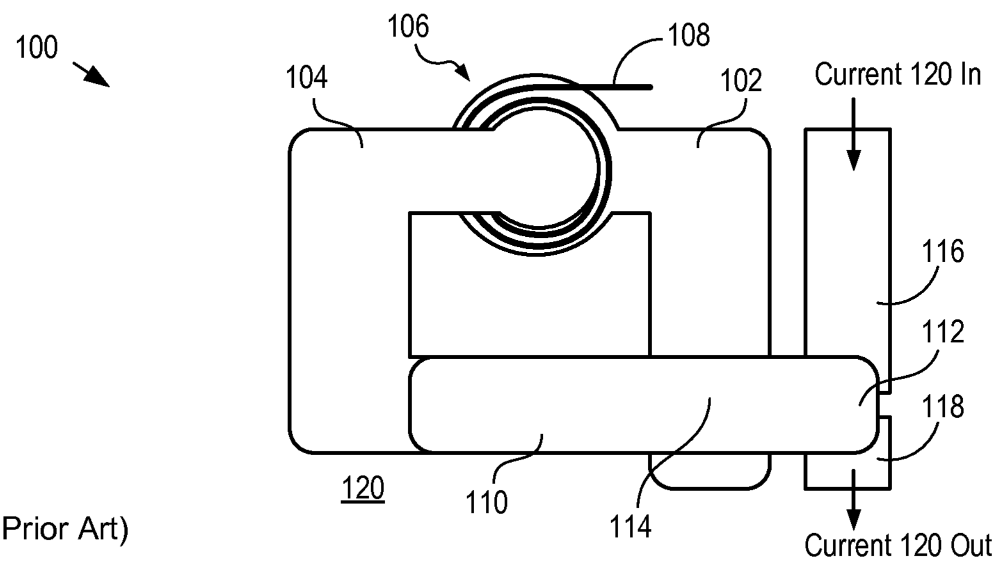


FIG. 1 (Prior Art)

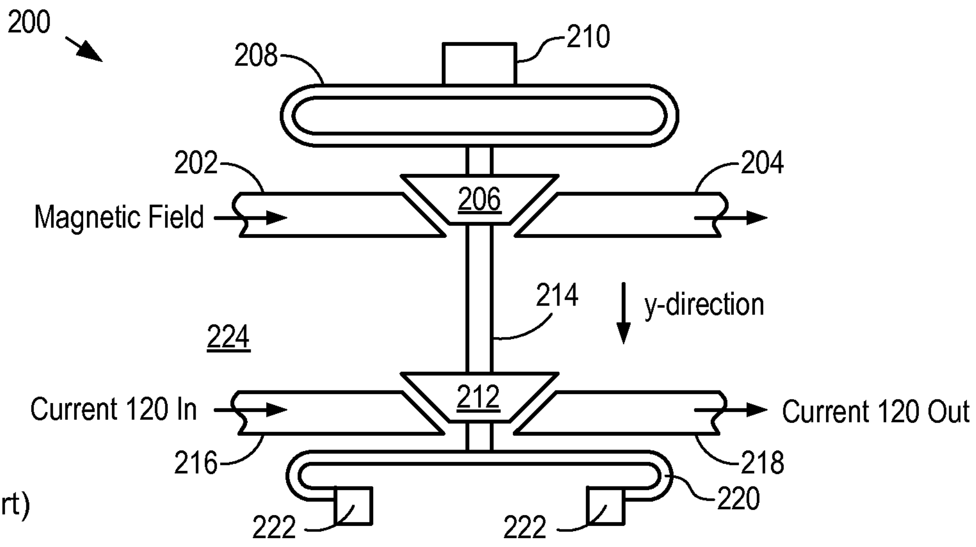


FIG. 2 (Prior Art)

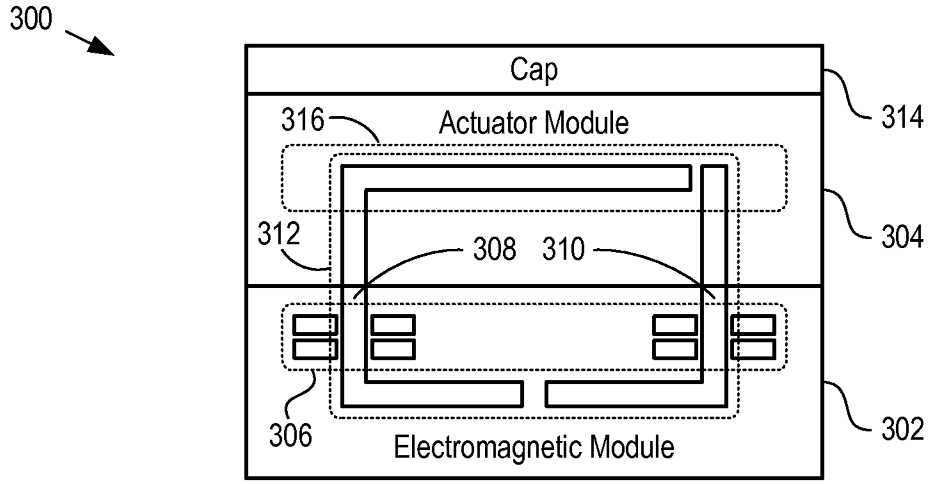

300
Cap
314
Actuator Module
316
304
312
308
310
306
Electromagnetic Module
302

FIG. 3

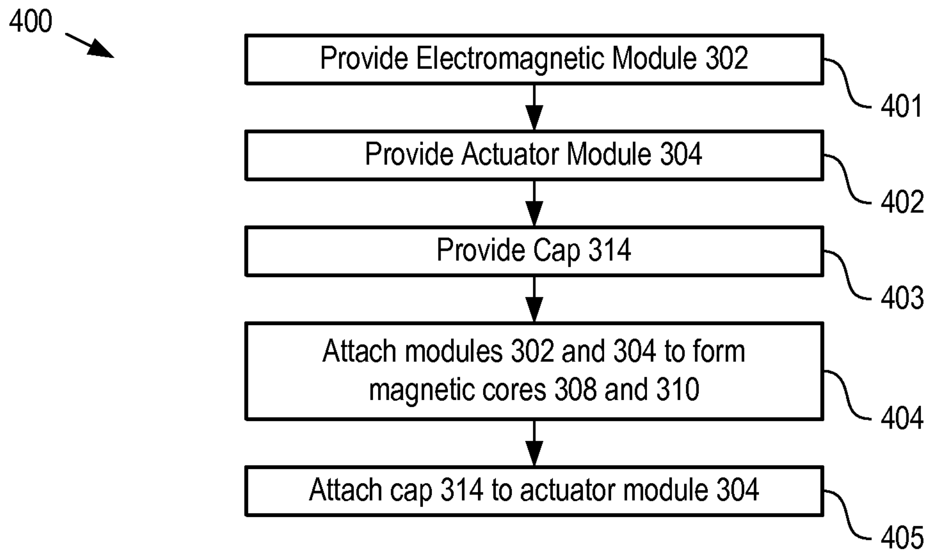

400
Provide Electromagnetic Module 302
401
Provide Actuator Module 304
402
Provide Cap 314
403
Attach modules 302 and 304 to form magnetic cores 308 and 310
404
Attach cap 314 to actuator module 304
405

FIG. 4

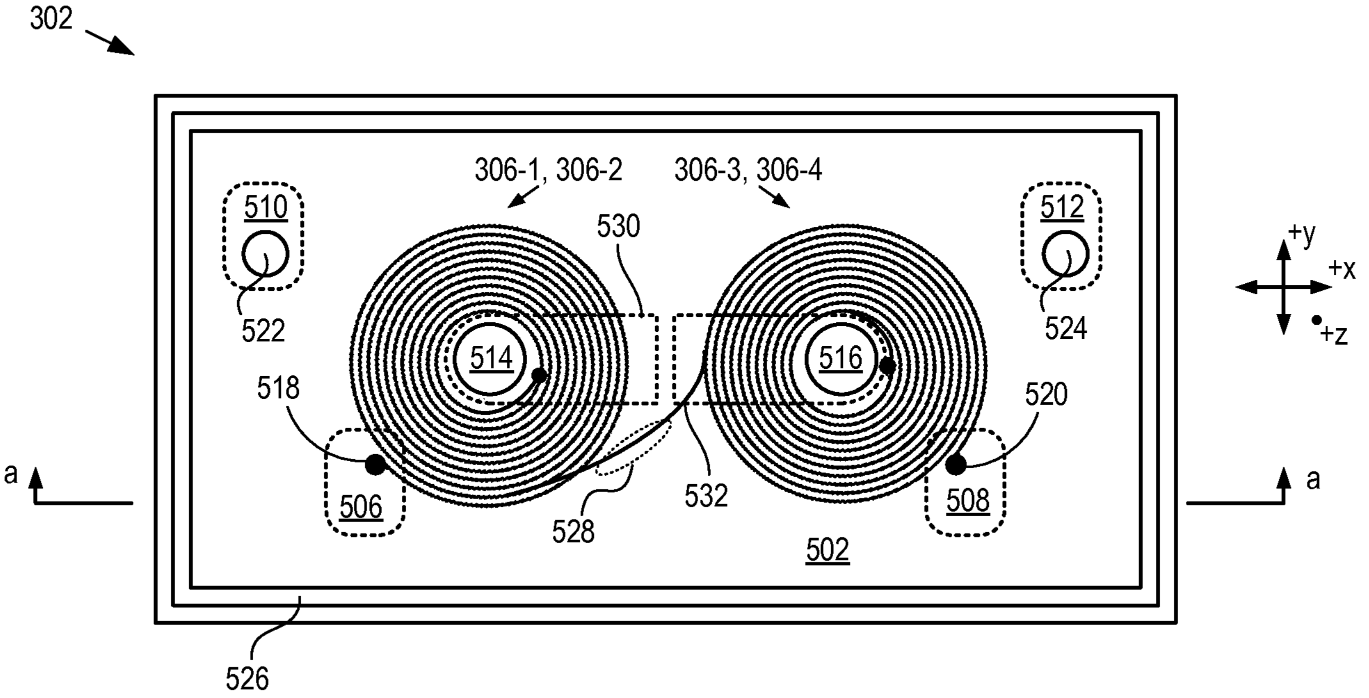

302
306-1, 306-2
306-3, 306-4
530
510
512
+y
+x
+z
522
524
514
516
518
520
a
a
506
508
528
532
502
526

FIG. 5A

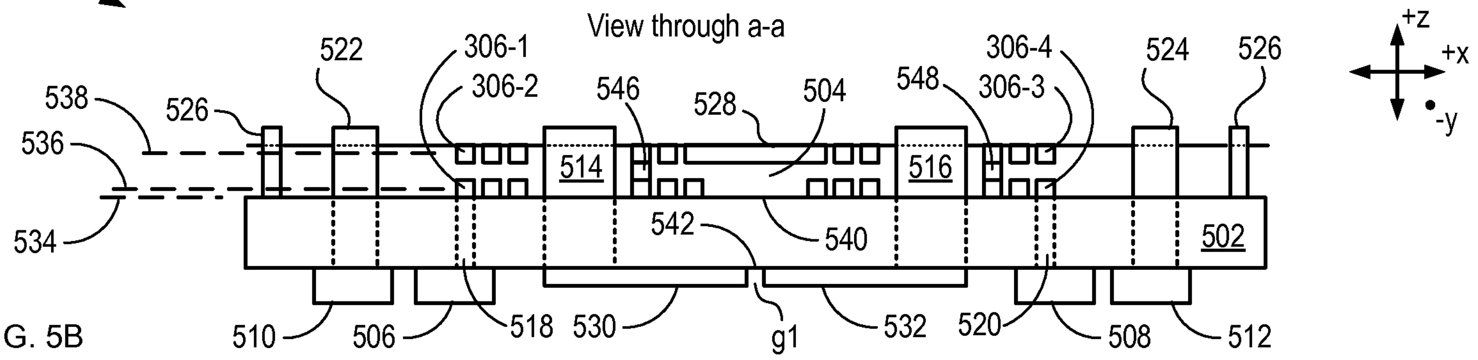

302
View through a-a
+z
+x
-y
522
306-1
306-2
546
528
504
548
306-3
306-4
524
526
538
526
536
534
514
516
502
542
540
510
506
518
530
g1
532
520
508
512

FIG. 5B

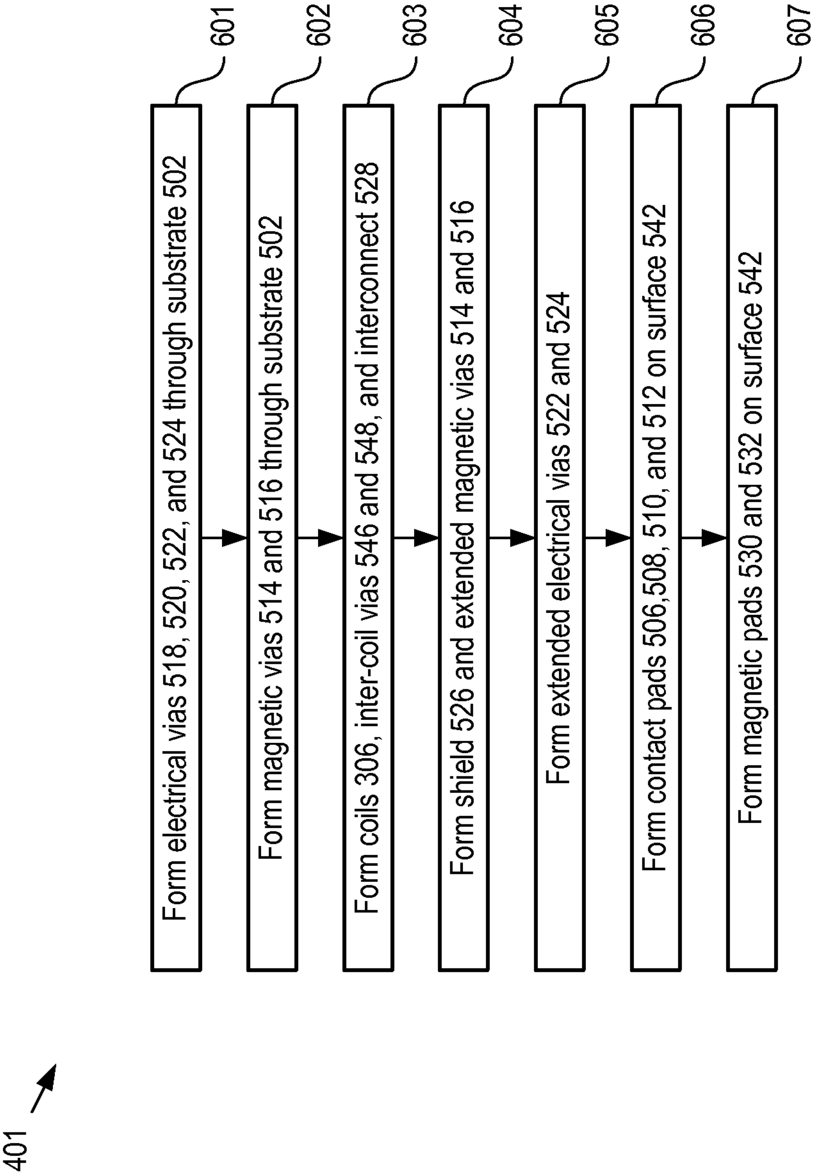

401
601
Form electrical vias 518, 520, 522, and 524 through substrate 502
602
Form magnetic vias 514 and 516 through substrate 502
603
Form coils 306, inter-coil vias 546 and 548, and interconnect 528
604
Form shield 526 and extended magnetic vias 514 and 516
605
Form extended electrical vias 522 and 524
606
Form contact pads 506,508, 510, and 512 on surface 542
607
Form magnetic pads 530 and 532 on surface 542

FIG. 6

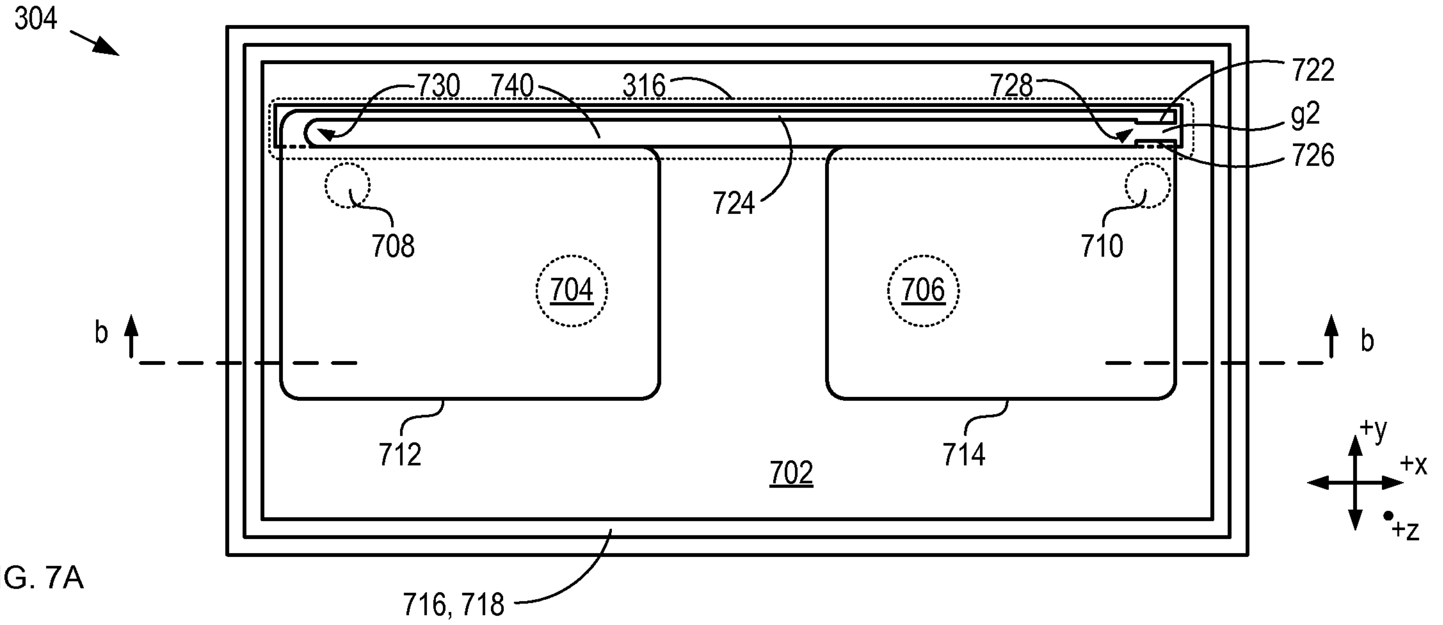

304
730
740
316
728
722
g2
726
724
708
710
704
706
b
b
712
714
702
+y
+x
+z
716, 718

FIG. 7A

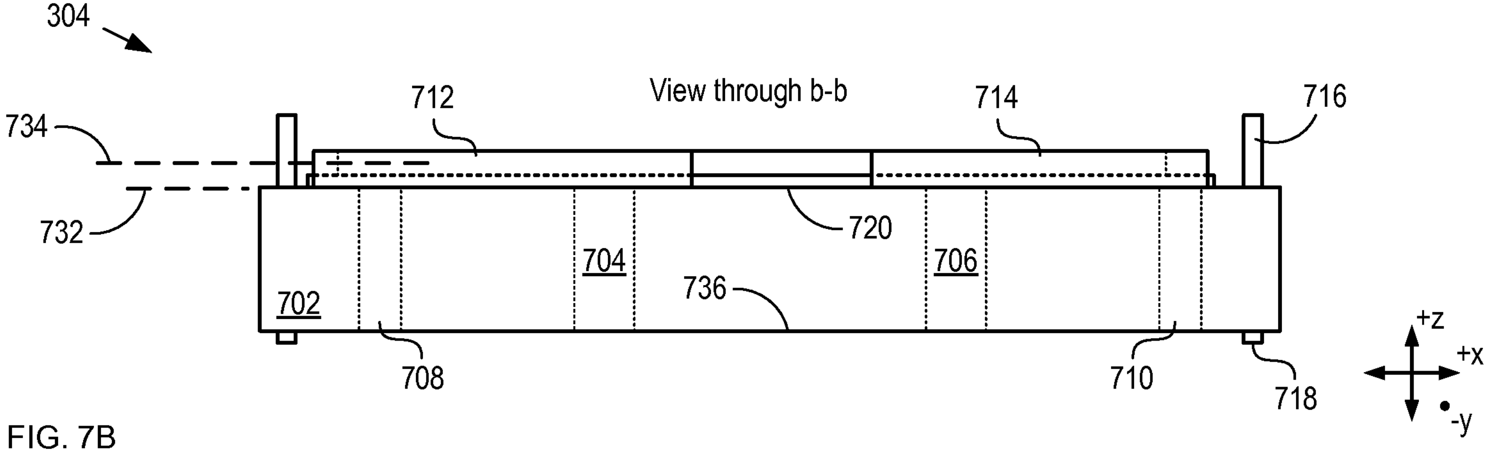
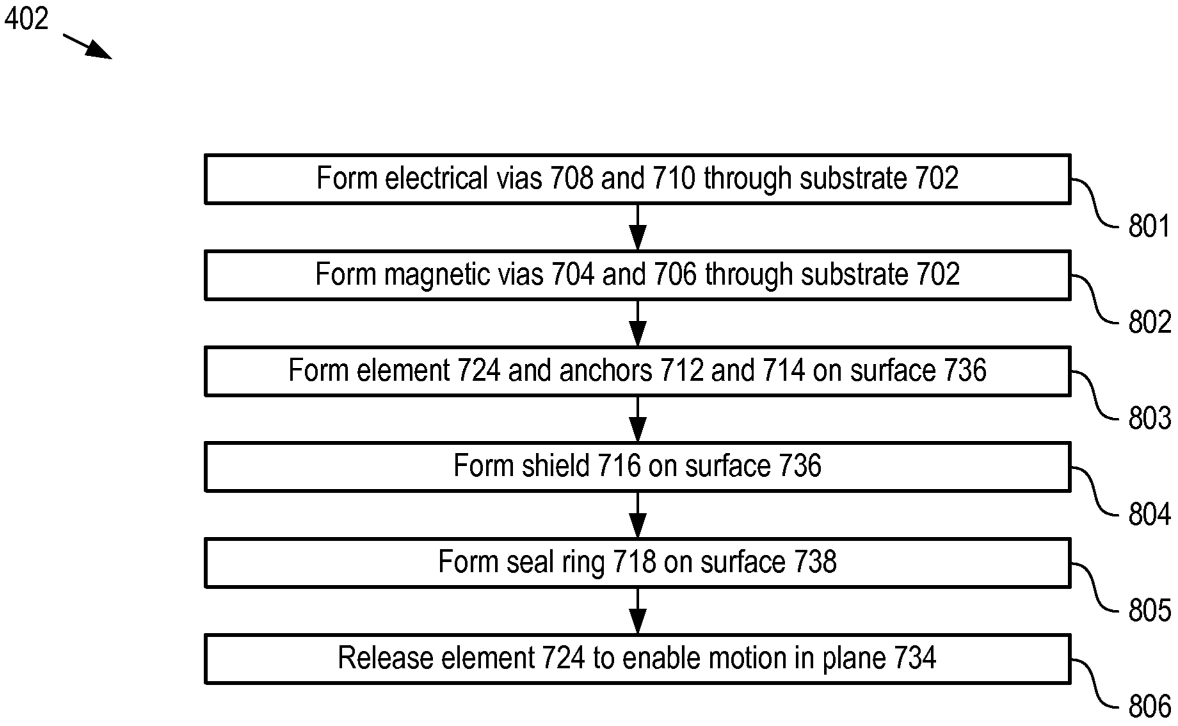

304
View through b-b
734
712
714
716
732
720
704
706
736
702
708
710
718
+z
+x
-y

FIG. 7B

FIG. 8


402
Form electrical vias 708 and 710 through substrate 702
801
Form magnetic vias 704 and 706 through substrate 702
802
Form element 724 and anchors 712 and 714 on surface 736
803
Form shield 716 on surface 736
804
Form seal ring 718 on surface 738
805
Release element 724 to enable motion in plane 734
806

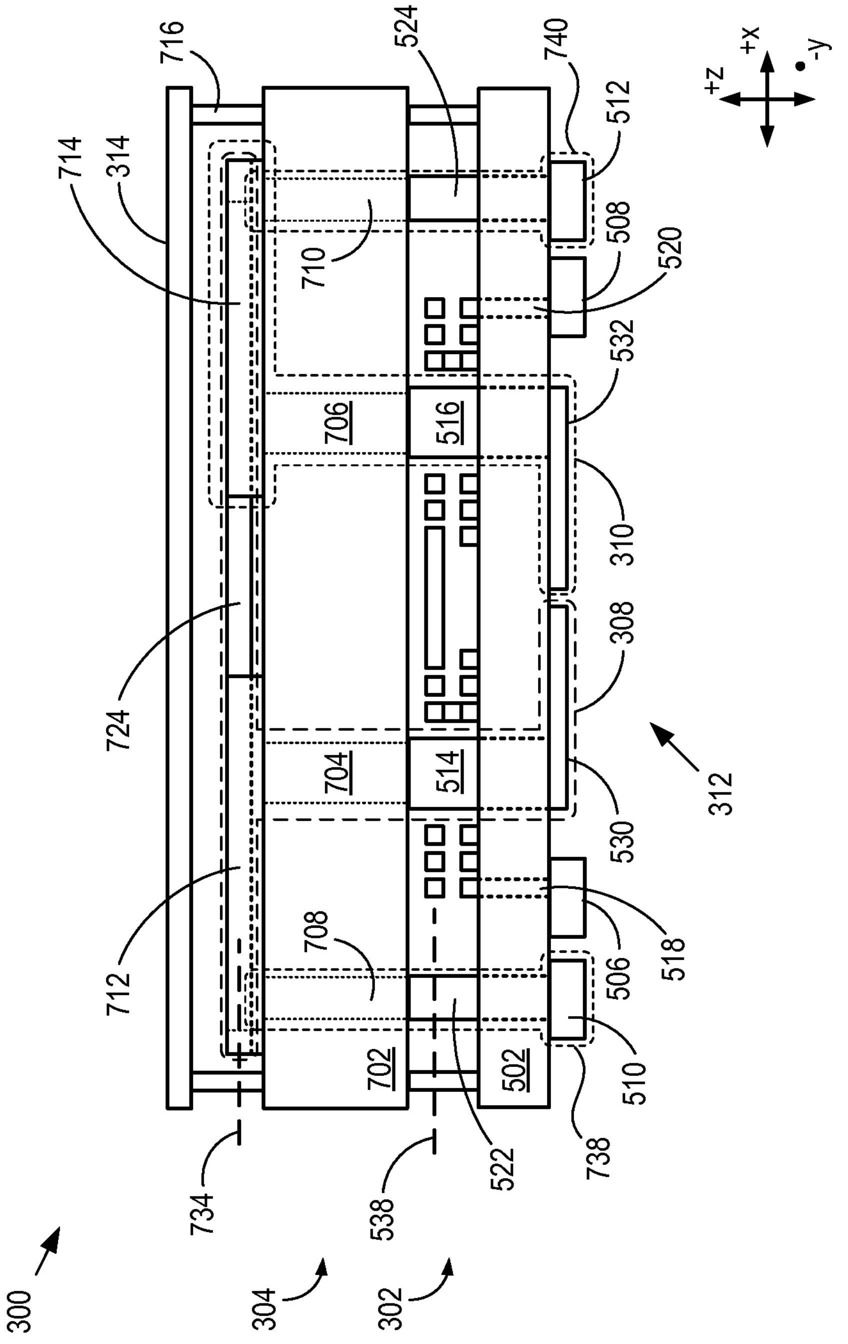

716
714
314
524
740
512
508
520
532
310
308
530
312
518
506
510
738
522
538
734
300
304
302
712
724
708
710
706
704
702
516
514
502
+x
-y
+z

FIG. 9

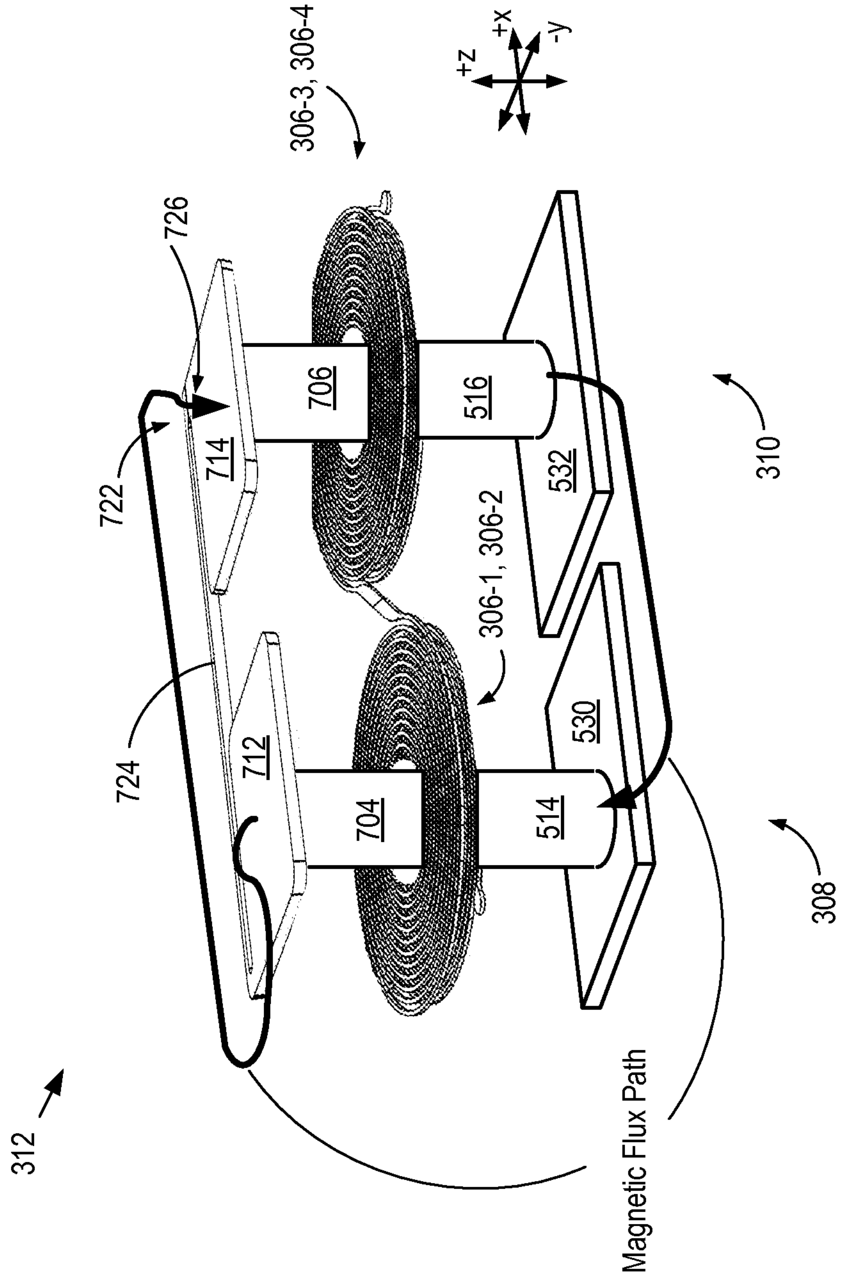

306-3, 306-4
+z
+x
-y
726
722
714
706
516
532
310
306-1, 306-2
724
712
704
514
530
308
312
Magnetic Flux Path

FIG. 10

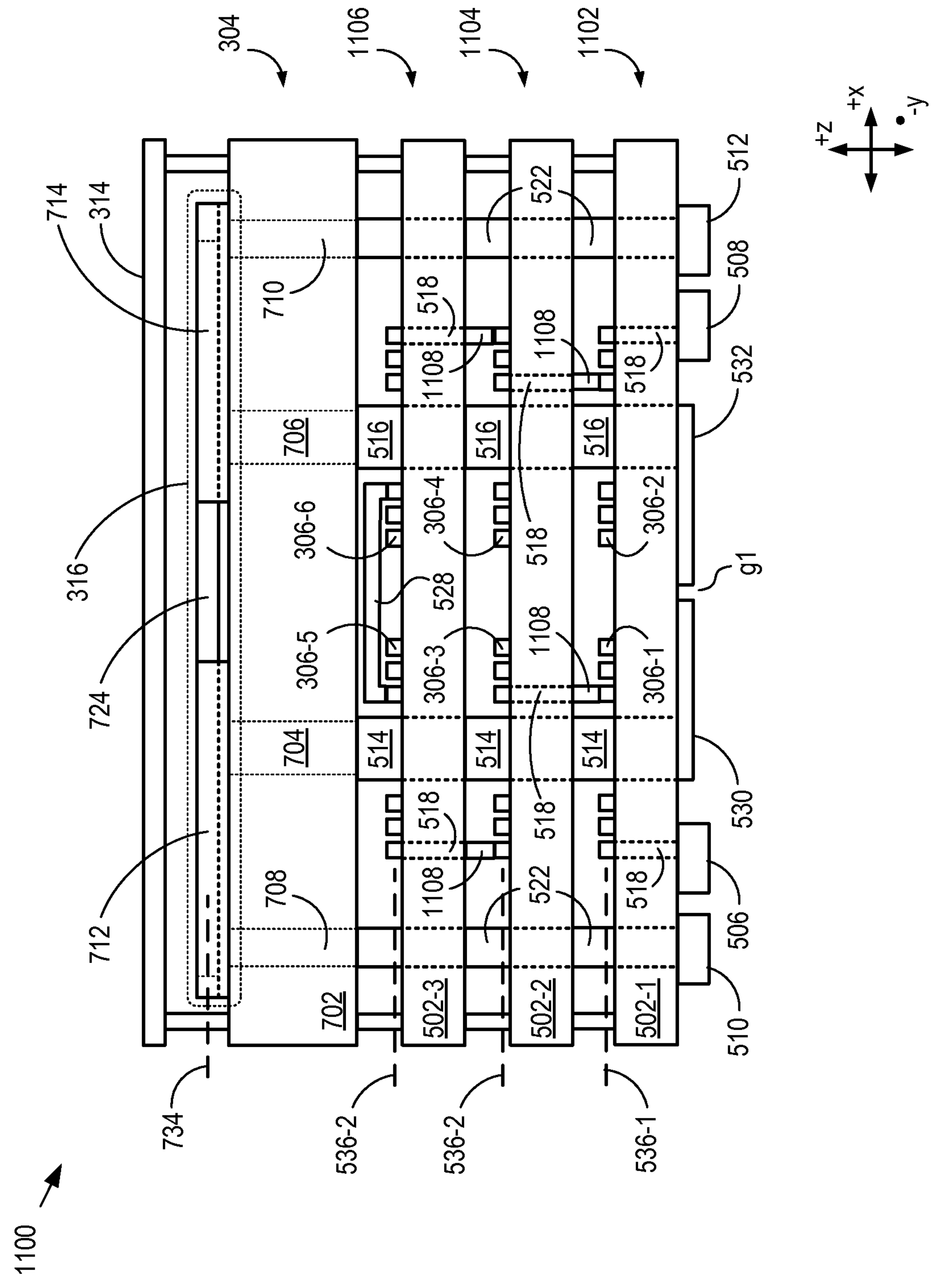

1100
304
1106
1104
1102
+x
-y
+z
714
314
316
724
712
734
710
706
704
702
708
516
514
518
1108
522
306-1
306-2
306-3
306-4
306-5
306-6
528
502-1
502-2
502-3
512
508
532
g1
530
506
510
536-1
536-2
536-2

FIG. 11

INTERNATIONAL SEARCH REPORT

International application No

PCT/US2011/027930

A. CLASSIFICATION OF SUBJECT MATTER

INV. H01H1/66 H01H50/00

ADD.

According to International Patent Classification (IPC) or to both national classification and IPC

B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)

H01H

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practical, search terms used)

EPO-Internal

C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category*	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
X	DE 100 31 569 A1 (ADVANTEST CORP [JP]) 1 February 2001 (2001-02-01) column 7, line 38 - line 41; figures 33-39	1-4,7,8, 12,13, 15-17, 19,20
X	US 6 924 966 B2 (PROPHET ERIC M [US]) 2 August 2005 (2005-08-02) column 13, line 22; figure 10	1,15
X	US 6 410 360 B1 (STEENBERGE ROBERT W [US]) 25 June 2002 (2002-06-25) the whole document	1,15

☐ Further documents are listed in the continuation of Box C.

☒ See patent family annex.

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"T" later document published after the international filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention

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"Y" document of particular relevance; the claimed invention cannot be considered to involve an inventive step when the document is combined with one or more other such documents, such combination being obvious to a person skilled in the art.

"&" document member of the same patent family

Date of the actual completion of the international search 31 May 2011	Date of mailing of the international search report 09/06/2011
Name and mailing address of the ISA/ European Patent Office, P.B. 5818 Patentlaan 2 NL - 2280 HV Rijswijk Tel. (+31-70) 340-2040, Fax: (+31-70) 340-3016	Authorized officer Socher, Günther

INTERNATIONAL SEARCH REPORT

Information on patent family members

International application No
PCT/US2011/027930

Patent document cited in search report		Publication date	Patent family member(s)			Publication date
DE 10031569	A1	01-02-2001	NONE			
US 6924966	B2	02-08-2005	AU	2003276830	A1	23-01-2004
			CN	1656644	A	17-08-2005
			GB	2405995	A	16-03-2005
			JP	2005527963	T	15-09-2005
			WO	2004006295	A2	15-01-2004
			US	2003223174	A1	04-12-2003
US 6410360	B1	25-06-2002	AU	2741900	A	07-08-2000
			WO	0044020	A2	27-07-2000